

Article

# High Resolution Magnetolectric Sensor and Low-frequency Measurement using Frequency up-conversion Technique

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**Abstract:** Magnetolectric (ME) sensor is a new type magnetic sensor with ultrahigh sensitivity, low power consumption, and suitable for the measurement of low frequency weak magnetic field. In this study, metglas/PZT-5B ME sensor with a mechanical resonance frequency  $f_{res}$  of 60.041 kHz was prepared. It is interesting to note that its magnetic field resolution reaches 0.20 nT at  $f_{res}$  and 0.34 nT for DC field, respectively. In order to measure the ultralow frequency AC magnetic fields, a frequency upconversion technique was employed. Under this technique, a limit of detection (LOD) of AC magnetic field lower than 1 nT at 8 Hz is obtained, and the minimum LOD of 0.51 nT is achieved at 20 Hz. The high resolution ME sensor with sub-pT level is promising in the field of low frequency weak magnetic field measurement technology.

**Keywords:** magnetolectric sensors; frequency upconversion technique; piezomagnetic material; low-frequency weak magnetic field

## 1. Introduction

With the development of the information age, the internet of things in the world requires all kinds of sensors to accurately detect the physical properties of different substances, leading to a widely application of sensors. For example, microelectro mechanical systems (MEMS) sensors can work in a variety of environments [1-6]. The magnetic sensor is one kind of the most important sensors. According to the working principle, magnetic sensors can be divided into the following types: magnetoresistance-type (for example, anisotropic magnetoresistance, giant magnetoresistance, tunneling magnetoresistance), magnetic-flux-type (flux-gate magnetometer, optic-pumping atomic magnetometer, proton precession magnetometer, and superconducting quantum interference devices), magnetic-field-type (giant magnetoimpedance, magnetoelectric coupling sensor), and so on. The magnetoresistance-type sensors have relatively lower magnetic field resolution. The magnetic-flux-type sensors exhibit very high magnetic field resolution, but the magnetic field resolution strongly depends on the dimension of the sensors. The reduction of dimension will result in a dramatically deterioration of magnetic field resolution [7-10]. In contrast, the magnetic-field-type sensors are proportional to the field intensity, not as strongly dependent on the sensor dimension as flux-type one [11-13]. Therefore, the ME sensor is very beneficial for the miniaturization and integration. At present, ME sensors have been used for non-contact positioning and navigation, such as geomagnetic field detection and brain magnetic field imaging [14-20].

ME sensors, based on the magnetolectric coupling effect, can timely transmit the magnetic field signals to a voltage, mediated in the interfacial stress  $\sigma$  [3, 21-24]. A good ME sensor should have a high ME coupling coefficient  $\alpha_{ME}$ , thus a large output voltage is available under a certain external magnetic field. The ME conversion efficiency reaches a maximum when the frequency of the external AC field is close to the mechanical resonance frequency  $f_{res}$  of the sensor. A DC bias magnetic field  $H_{bias}$  usually exerts to the

piezomagnetic layer to maximize the piezomagnetic coefficient  $d_m$ . Therefore, the best magnetic field sensitivity of ME sensor with an optimized  $\alpha_{ME}$  should be working at  $f_{res}$  under an optimal DC bias magnetic field [10, 25-28]. Recently, the research work is focused on reducing  $f_{res}$  and improving  $\alpha_{ME}$  of the ME sensors. E. Quandt in Kiel University, Germany enhanced the magnetoelectric coupling coefficient up to  $|\alpha_{ME}|_{max} = 6.9 \text{ kV/cm} \cdot \text{Oe}@H_{bias} = 2.4 \text{ Oe}$  in AlN/FeCoSiB thin film sensor by adjusting the resonance frequency range of Si cantilever beam [29].

In general, the frequency of weak magnetic field to be measured is usually lower than 1 kHz (such as, magnetoencephalography, magnetocardiography, and underwater/underground mineral resources), while the typical operating frequency ( $f_{res}$ ) of bulk ME sensor is several tens of kHz. Moreover, the magnetic field resolution dramatically reduces with deviation from the  $f_{res}$ . In order to sensitively measure ultra-low frequency magnetic field signals by using ME sensor vibrating at resonant frequency  $f_{res}$ , a frequency upconversion technique is employed in this study. If a low-frequency ( $f_{tbm}$ ) magnetic field to be measured is exerted on the ME sensor vibrating at its mechanical resonance  $f_{res}$ , two shoulder peaks will appear on both sides of the main peak at the resonance frequency  $f_{res}$  after Fourier transform. The frequency shifts from the main peak are  $\pm f_{tbm}$ , respectively, and the peak height was proportional to the measured magnetic field. After magnetic field calibration, the magnitude of the measured low frequency weak magnetic field signal can be obtained via measuring the height of the shoulder peaks [30-33]. In general, the limit of detection (LOD) depends on the dimension of ME sensor and the operating frequency, and the LOD for the thin-film sensor is better than that of bulk one, and the LOD for AC field is smaller than that for DC one as well. For example, the LOD of AC magnetic field for metal glass/lead niobium magnesium-Lead titanate (Metglas/PMN-PT) sensor, reported by S. Zhang in University of Wollongong, is 2 pT, while that of DC magnetic field is only 200 pT [34]. Z. Chu in Peking University also reported a LOD of 115 pT in a Metglas/PMN-PT sensor at 10 Hz [35].

As for the thin-film ME sensors, they are promising because of their lower operating frequency and magnetic field sensitivity. E. Quandt in Kiel University widely studied the film ME sensors composed of soft magnetic films and AlN ferroelectric layer. He reported that the magnetoelectric properties of AlN/FeCoSiB can be regulated by adjusting NiTi substrate, a very low frequency of 273 Hz and a LOD of  $110 \text{ pT}/\sqrt{\text{Hz}}$  were obtained. In addition, an ultrahigh sensitivity of  $64 \text{ kV/T}$  under a zero bias magnetic field was obtained through the converse ME modulation of thin-film Si cantilever composites, the LOD of  $210 \text{ pT}/\sqrt{\text{Hz}}$  at 1 Hz and  $70 \text{ pT}/\sqrt{\text{Hz}}$  at 10 Hz were achieved. Even for similar systems, a linear resolution of 1.2 nT at 200 mHz can be obtained by combining mesoscale thin film cantilever beams with pickup coil readout [18,27,36,37]. However, thin-film ME sensors require complex micromachining techniques and have a high cost. The preparation of bulk ME sensor is simple, the technology is flexible, and it has a good development prospect. Therefore, this study focuses on exploring the bulk ME sensor and its measurement method.

## 2. Experimental

A FeCoSiB metglas sheet with dimension of  $22^{\text{length}} \times 2^{\text{width}} \times 0.03^{\text{thickness}} \text{ mm}^3$  was bonded to a lead zirconate titanate  $\text{Pb}(\text{Zr},\text{Ti})\text{O}_3$ -5B (PZT-5B) sheet with dimension of  $25 \times 2 \times 0.5 \text{ mm}^3$  using AB epoxy adhesive produced by 3M company. The PZT-5B sheet is 3 mm longer than Metglas sheet because the reserved part of PZT-5B was used to stick the enameled wire to measure the output ME voltage. The upper and lower sides of PZT are coated with silver glue in advance, and then the piezoelectric PZT-5B was polarized in the thickness direction under a voltage of 3.0 kV.

The performance of the ME sensor were carried out by a home-made ME test system, as shown in Figure 1. The prepared ME sensor is put in a long-straight solenoid magnetic field generator. An AC voltage signal provided by a lock-in amplifier (Stanford, model

SR830) was amplified by a power amplifier, then input into the above long-straight solenoid to generate AC magnetic field  $H_{ac}$ . The long-straight solenoid is placed along the axis center of the Helmholtz coils. The DC bias magnetic field  $H_{bias}$  was generated by the Helmholtz coils supplied by a DC power supply (YL2420). The variation of  $H_{ac}$  (also called the magnetic field to be measured  $H_{tbn}$ ) will cause a strain in the piezomagnetic metglas (FeCoSiB amorphous ribbon in this study) due to the magnetostrictive effect. This strain will exert on the piezoelectric PZT-5B through the AB epoxy adhesive, leading to a voltage via the piezoelectric effect, mediated by the interface stress. The output voltage of ME sensor is amplified by the lock-in amplifier, then transmitted and processed by a home-made Labview program. This measurement instrument is used to explore some performances of ME sensors, for example, to find out the optimal working point, including the mechanical resonance frequency  $f_{res}$  and DC bias field  $H_{bias}$ , and to measure the LOD, magnetic field resolution and sensitivity of ME sensors. In addition, the magnetic field resolution of DC and AC field at  $f_{res}$  or ultra-low frequencies of ME sensors can be measured by improving the instrument. Under a certain DC field (around the optimal DC bias field), the output voltage  $V_{out}$  versus frequency ( $V_{out}-f$ ) curve can be obtained by scanning the frequency from 0 to 100 kHz. The frequency at the peak of  $V_{out}-f$  curve is the mechanical resonance frequency  $f_{res}$ . After that, setting the lock-in amplifier at  $f_{res}$  and scanning the DC field H, the  $V_{out}-H$  curve can be obtained. The magnetic field at the maximum  $V_{out}$  is the optimal magnetic field the optimal  $H_{bias}$ .

### 2.1. AC field resolution at $f_{res}$

Set the frequency of lock-in amplifier at  $f_{res}$ . The AC magnetic field strength  $H_{ac}$ , exerted on the ME sensor, can be tuned by the output voltage of the lock-in amplifier. For a fixed  $H_{ac}$ , a stable ME output voltage  $V_{out}$  can be obtained from the lock-in amplifier. Thus, a  $V_{out}$  platform will be appeared in  $V_{out}$ -time curve. Since  $V_{out}$  is proportional to  $H_{ac}$ , decreasing H gives rise to a series of steps in the  $V_{out}$ -time curve. The AC field resolution limit can be approaching by decreasing  $H_{ac}$  till the steps are indistinguishable.

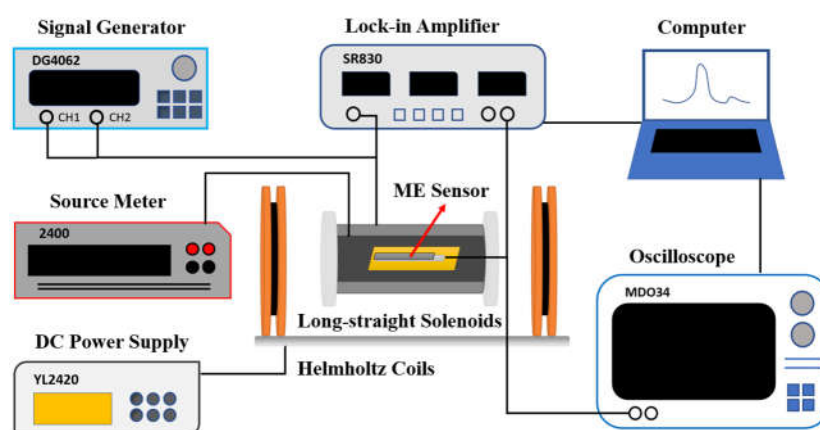
### 2.2. DC field resolution

To test the DC field resolution, the ME sensor is put into the center of an additional small solenoid, and then they are put into the center of the long-straight solenoid. The DC magnetic field, as a field to be measured  $H_{tbn}^{DC}$ , is generated by this small solenoid, supplied by Keithley 2400 source meter, while the driving AC magnetic field with frequency of  $f_{res}$  is still provided by the long-straight solenoid, supplied by lock-in amplifier. The optimal DC bias field  $H_{bias}$  is also generated by Helmholtz coils. Therefore, at this moment, the ME sensor is working at  $f_{res}$  and at field of  $H_{bias}+H_{tbn}^{DC}$ . Since the  $H_{tbn}^{DC}$  is much smaller than  $H_{bias}$ , the ME sensor actually operates in the perturbation state of the optimal DC bias field. Reduce the  $H_{tbn}^{DC}$  till the  $V_{out}$ -time step becomes indistinguishable, and the minimum value of  $H_{tbn}^{DC}$  (i.e. the DC field resolution) can be found out.

### 2.3. AC field resolution at ultralow frequency

During the measurement of AC field resolution at ultralow frequency, the AC magnetic field power supply of lock-in amplifier is replaced by a signal generator (RIGOL DG2102) because the signal generator is easier to adjust the signal modulation frequency and depth. However, the  $V_{out}$  of the ME sensor is still received and processed by SR830 lock-in amplifier. Although a high AC magnetic field resolution can be achieved at  $f_{res}$ , it will dramatically reduce when the operating frequency is deviated from  $f_{res}$ . This can be attributed to the rapid reduction of ME coupling efficiency. This characteristic of ME sensor shows that it is not suitable for the direct measurement of ultra-low frequency magnetic field. Therefore, it is necessary to find out a way to measure the ultralow frequency magnetic field by taking advantage of the extremely high sensitivity of the ME sensors. In this study, a frequency up-conversion technique (FUCT) was proposed for measuring the

ultralow frequency magnetic field using ME sensor. The signal generator outputs two signals of different frequencies, one with the frequency of  $f_{res}$  as the reference signal, and the other as the signal to be measured  $H_{tbn}^{AC}$  with very low frequency ( $f_{ac}=8$  Hz for instance). A mixed signal modulated by the low frequency signal is fed into a long straight solenoid, which in turn applies the resulting magnetic field to the ME sensor. The output voltage from the ME sensor is picked up by an oscilloscope (Tektronix MDO34), instead of a lock-in amplifier. It can be seen that two voltage shoulder peaks will appear in the left ( $f_{res}-f_{ac}$ ) and right ( $f_{res}+f_{ac}$ ) around  $f_{res}$ , respectively, with a frequency shift  $\Delta f$  of  $\pm f_{ac}$  from  $f_{res}$ . The voltage amplitude of the shoulder peak is proportional to the strength of the low-frequency modulation field  $H_{tbn}^{AC}$ . The AC field resolution  $H_{rsl}^{AC}$  can be obtained by reducing the low-frequency  $H_{tbn}^{AC}$  till the shoulder peaks are undetectable. Change the modulation frequency, and repeat the above operation, the frequency dependence of  $H_{rsl}^{AC}$  can be obtained.



**Figure 1.** The schematic show of the principle of the ME test system (The actual wiring method can be adjusted according to the test types).

### 3. Results and discussion

The AC field frequency dependence of  $V_{out}$  of the ME sensor was detected by scanning the AC field frequency in the range of 1-70 kHz under zero DC bias field (Figure 2a). The center frequency of 60.041 kHz was observed. However, when the AC field frequency is scanned under a DC bias field of 2.5 Oe, the peak frequency is shifted from 60.041 kHz to 60.101 kHz (Figure 2b). The resonance peak shift can be attributed to the influence of magnetic field on the Young's modulus, i.e. the delta-E effect [38-40]. Comparing Figure 2a and 2b, it is interesting to note that the  $V_{out}$  at  $H_{bias}=2.5$  Oe is dramatically enhanced by twice than that at zero field.

In order to search the optimal DC bias magnetic field, the DC field was scanned in the range of 0-15 Oe under a resonance frequency of 60.101 kHz. Figure 3 shows the  $V_{out}-H_{dc}$  curve and its differential. As illustrated, the  $V_{out}$  reaches the maximum around 2.5 Oe. Therefore, 2.5 Oe is the optimal DC bias field for AC magnetic field measurement ( $H_{bias}^{AC}$ ). The differential ( $dV_{out}/dH_{dc}$ ) curve of  $V_{out}-H_{dc}$  relationship represents the variation rate of the  $V_{out}$  with the external DC magnetic field. The magnetic field at the maximum of the differential curve ( $dV_{out}/dH_{dc})_{max}$  is the optimal bias field for the DC magnetic field measurement ( $H_{bias}^{DC}$ ), where the output voltage is most sensitive to the variation of DC magnetic field. From Figure 3, it can be seen that ( $dV_{out}/dH_{dc})_{max}$  occurs at 0.5 Oe (i.e.  $H_{bias}^{DC}=0.5$  Oe).

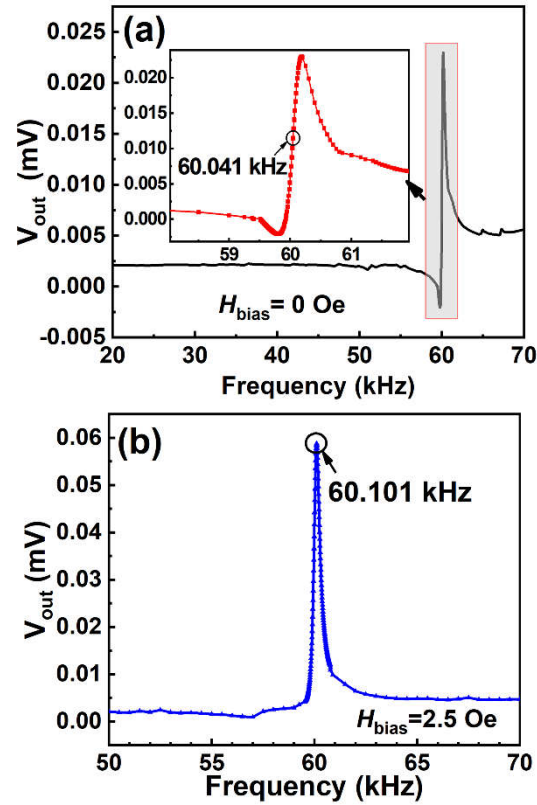


Figure 2. The frequency dependence of the  $V_{out}$  of the ME sensor without DC bias field  $H_{bias}=0$  Oe (a) and with  $H_{bias}=2.5$  Oe (b). The inset of Figure 2a is a magnified view of the vicinity of the resonance peak.

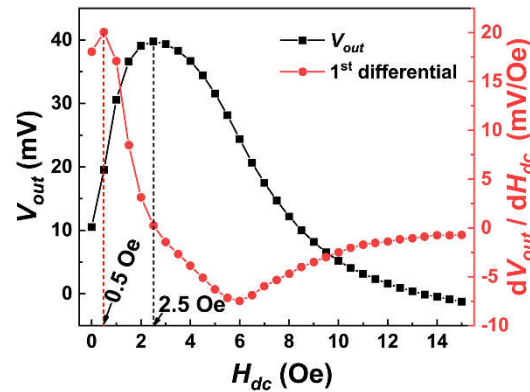


Figure 3. The  $V_{out}$ - $H_{dc}$  curve and its differential curve at  $f_{res}$  of 60.101 kHz.

The resonant frequency of 60.101 kHz and the bias field of 2.5 Oe are adopted as the working point for AC field resolution measurement. The  $V_{out}$ -time steps at various input AC fields are shown in Figure 4. The absolute height of  $V_{out}$ -time step refers to the output voltage  $V_{out}$  at a certain AC voltage input to the long-straight solenoid, which can be converted to the input AC magnetic field intensity  $H_{in}$  after calibration. Thus the relative height of the neighboring  $V_{out}$ -time steps can be converted as the difference of AC field  $\Delta H_{in}$ . In other word, if the  $H_{in}$  is continuously reduced till the step height is indistinguishable, the corresponding  $\Delta H_{in}$  is the resolution limit of the AC magnetic field  $H_{rsl}^{AC}$ . As illustrated in Figure 4, an excellent  $H_{rsl}^{AC}$  of 0.2 nT was obtained at resonance frequency of 60.101 kHz.

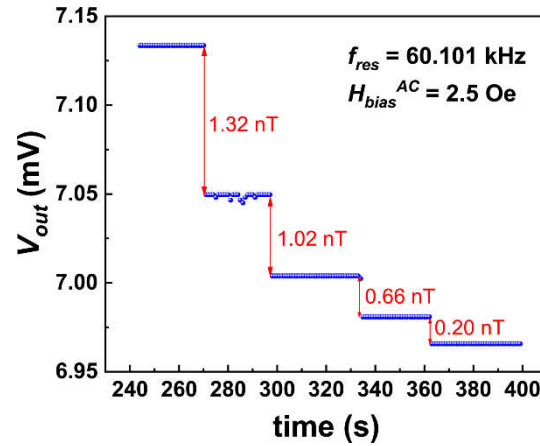


Figure 4. AC magnetic field resolution at  $f_{res}$  of 60.101 kHz and  $H_{bias}^{AC}$  of 2.5 Oe.

Similarly, the DC field resolution  $H_{rsl}^{DC}$  can be obtained under the working point with  $f_{res}=60.101$  kHz and  $H_{bias}^{DC}=0.5$  Oe, as shown in Figure 5. The red dotted line represents the output voltage  $V_{out}$  of the ME sensor operating at the above working point without the DC perturbation magnetic field [ $(V_{out})_0$ ], which can be used as a reference voltage without input DC magnetic field. The optimal DC bias field  $H_{bias}^{DC}=0.5$  Oe is supplied by the Helmholtz coils. The DC field to be measured  $H_{tbn}^{DC}$ , which has an opposite direction with the  $H_{bias}^{DC}$ , is generated by the small solenoid, supplied by Keithley 2400 source meter. If a  $H_{tbn}^{DC}$  (for example 5.0 nT) exerts on the ME sensor, the  $V_{out}$ -time step will decrease from 5.97 mV to 2.91 mV (Figure 5). If the DC input field  $H_{tbn}^{DC}$  is removed, the  $V_{out}$  is recovered to its original value. Gradually reducing the  $H_{tbn}^{DC}$  value till the  $V_{out}$ -time step cannot be distinguished from the base line, the DC magnetic field resolution  $H_{rsl}^{DC}$  will be obtained. As illustrated in Figure 5, a very low  $H_{rsl}^{DC}$  of 0.34 nT was achieved in this study. The [ $(V_{out})_0$ ] is close to the  $V_{out}$  under AC magnetic field measurement conditions, which indicates that the addition of a signal-free solenoid will cause a change in the corresponding magnetic field near the sensor, thereby changing the output signal; Moreover, the difference between the steps in Figure 5 and Figure 4 corresponds to different values, because different solenoids have different ability to convert magnetic fields, and the steps in measuring AC magnetic field are more stable than those in measuring DC magnetic field, indicating that the sensor has better ability to resist noise.

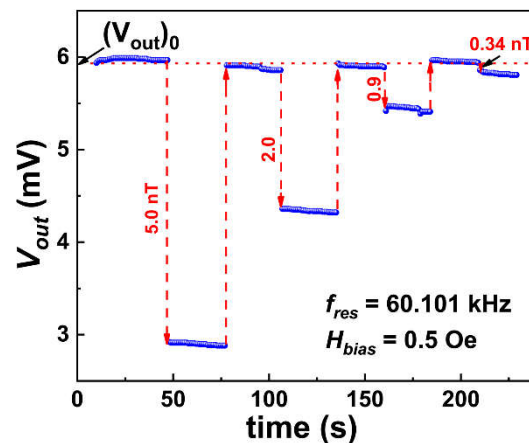
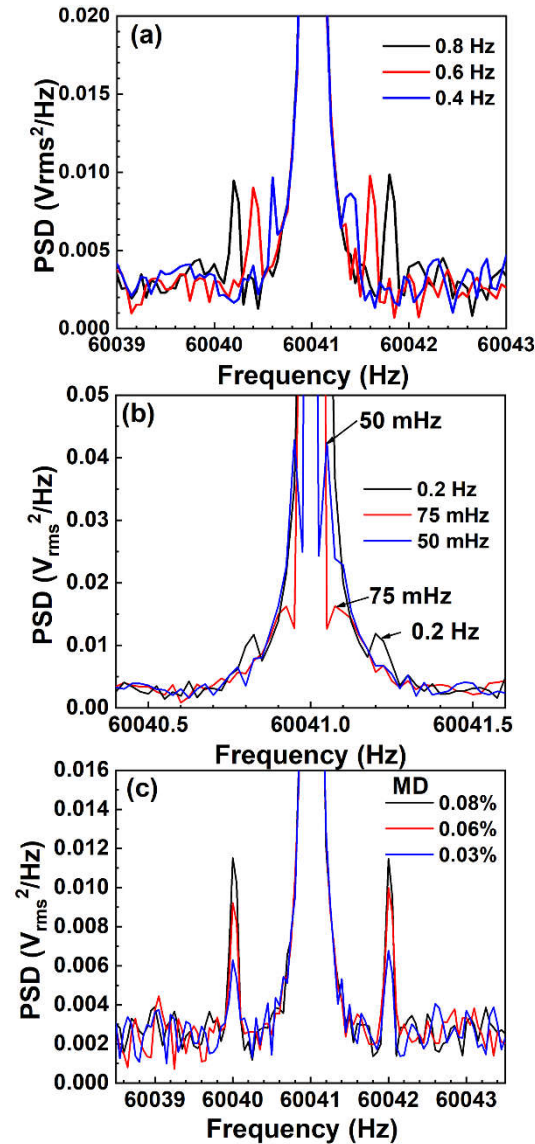


Figure 5. DC magnetic field resolution  $H_{rsl}^{DC}$  at  $f_{res}=60.101$  kHz and  $H_{bias}^{DC}=0.5$  Oe.



**Figure 6.** The modulation peaks at MD = 0.05% at various modulation frequencies (a) and (b), and at different MDs with a modulation frequency of 1 Hz (c).

As discussed above, the optimal AC field sensitivity of the ME sensors occurs at working point with  $f_{res} = 60.041 \text{ kHz} @ H_{bias}^{AC} = 2.5 \text{ Oe}$ . In order to measure the ultralow frequency field, a FUCT method was proposed. In this method, another magnetic field  $H_{tbm}^{AC}$  with a low frequency  $f_{tbm}$  as a field to be measured, was mixed with the AC exciting field  $H_{ac}$  at resonance frequency, leading to two shoulder peaks located at the left and right sides of the main peak with a frequency shift of  $\pm f_{tbm}$ . The intensity of the  $H_{tbm}^{AC}$  and the frequency  $f_{tbm}$  can be tuned by varying the modulation depth ( $MD = H_{tbm}^{AC} / H_{ac}$ ) and frequency of the signal source [30]. Figure 6a and 6b show the influence of the modulation frequency on location of the shoulder peaks at a MD of 0.5%. As illustrated in Figure 6a, although the operating frequency is higher than 60 kHz, the modulated shoulder peaks at frequency differences of 0.4, 0.6, 0.8 Hz are clearly distinguishable. If further decreasing the modulation frequency, a modulation signal with an ultralow frequency of 50 mHz also can be distinguished from the background signal (Figure 6b). This indicates that the measurement instrument can detect the ultralow frequency magnetic field with frequency as low as 50 mHz. If fixing a modulation frequency (1 Hz for instance), the peak voltage of the shoulder peaks is proportional to the MD (i.e. the  $H_{tbm}^{AC}$ ). The AC field resolution  $H_{rsi}^{AC}$  can be approaching by reducing the MD at the modulation frequency till the shoulder peaks cannot be distinguished from the background signal. Using this method,

the AC field resolutions  $H_{rsl}^{AC}$  in the frequency range from 80 Hz to 50 mHz were measured and summarized in Figure 7. As illustrated, the  $H_{rsl}^{AC}$  is dramatically deteriorated with the decreases of frequency. The  $H_{rsl}^{AC}$  rapidly increases from 0.45 nT@80 Hz to 51 nT@50 mHz. Nevertheless, for the frequency over 8 Hz, the  $H_{rsl}^{AC}$  of the ME sensor is better than 1 nT, which is an excellent achievement [5, 37, 41, 42].

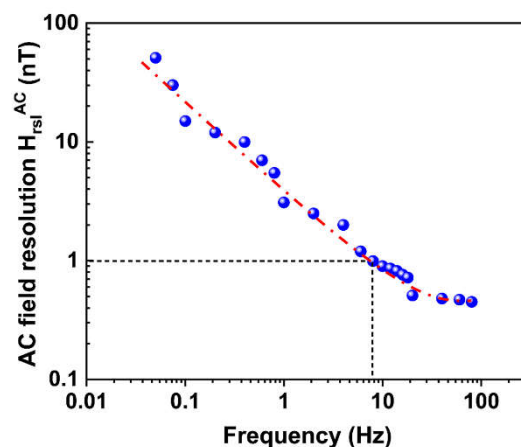


Figure 7. The AC magnetic field resolution at ultralow frequencies (the dash-dot line is guided for eyes).

#### 4. Conclusions

A FeCoSiB Metglas/PZT-5B magnetolectric coupling sensor with dimension of  $25 \times 2 \times 0.5$  mm<sup>3</sup> and resonance frequency of 60.101 kHz was fabricated for weak magnetic field measurement. It is interesting that excellent AC and DC magnetic field resolutions as low as 0.2 and 0.34 nT, respectively, were obtained. The frequency upconversion technique is an effective way to sensitively measure ultralow frequency AC magnetic field resolution. It is revealed that the AC field resolution is rapidly deteriorated with the decrease of frequency due to the far deviation from the resonance frequency. Nevertheless, an excellent AC field resolution is achieved, and the frequency of magnetic field resolution better than 1 nT consistently persists up to 8 Hz.

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